

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. KM1-004		PRIORITY SERIAL NO. 10/007,300	
LIST OF ART CITED BY APPLICANT <small>(Use several sheets if necessary)</small>					APPLICANT: Keiji Jono et al.			
					PRIORITY FILING DATE November 8, 2001		PRIORITY GROUP ART UNIT 2811	
U.S. PATENT DOCUMENTS								
Examiner's Initials	Class	Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate	
	AA	6,154,417 6,514,417	11/2000	Kim				
	AB	6,171,924	01/2001	Wang et al.				
	AC	6,258,688	07/2001	Tsai				
	AD	6,274,457	08/2001	Sakai et al.				
	AE	6,342,428	01/2002	Zheng et al.				
	AF	6,350,855	02/2002	Mizuo				
	AG	6,355,540	03/2002	Wu				
	AH	6,380,095	04/2002	Liu et al.				
	AJ	6,383,931	05/2002	Flanner et al.				
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
	AJ						Yes	No
	AK							
	AL							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
	AM	W. Tontu et al., <i>Impact of Shallow Trench Isolation on Reliability of Buried- and Surface-Chanel Sub-μm PFET</i> , IEEE, pp. 24-29 (1995).						
	AN							
	AO							
EXAMINER		DATE CONSIDERED 8/4/2006						
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>								